ROCHESTER INSTITUTE OF TECHNOLOGY MICROELECTRONIC ENGINEERING

Designers Manual for SMFL Standard CMOS

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Rochester Institute of Technology Microelectronic Engineering Revision Date: 11-8-06 SMFL_CMOS_Design.ppt

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OUTLINE

Introduction Crossection, Layout and Masks Process Detail List Design Layer Names I/O Cells Test Chip Spice Models References



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INTRODUCTION

RIT is supporting three different CMOS process technologies. The older p-well CMOS has been phased out. The SMFL-CMOS process is used for standard 5 Volt Digital and Analog integrated circuits. This is the technology of choice for teaching circuit design and fabricating CMOS circuits at RIT. The SUB-CMOS and ADV-CMOS processes are intended to introduce our students to process technology that is close to industry state-of-the-art. These processes are used to build test structures and develop new process technologies at RIT.

RIT p-well CMOS RIT SMFL-CMOS RIT Subµ-CMOS RIT Advanced-CMOS

$\lambda = 4 \ \mu m$
$\lambda = 1 \ \mu m$
$\lambda = 0.5 \ \mu m$
$\lambda = 0.25 \ \mu m$

 $Lmin = 8 \ \mu m$ $Lmin = 2 \ \mu m$ $Lmin = 1.0 \ \mu m$ $Lmin = 0.5 \ \mu m$

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DESIGN LAYER NAMES

POLY





RIT SMFL-CMOS PROCESS



SMFL-CMOS PROCESS

SMFL-CMOS, twin-well CMOS process, two level Metal

1. ID01 scribe 2. DE01 4 pt probe 3. CL01 4. OX05--- pad oxide 5. CV02-1500 Å 6. PH03 –1- n well, 7. ET29 nitride etch 8. IM01 – n-well 9. ET07 strip resist 10. CL01 11. OX04 – well oxide **12. ET19 strip nitride** 13. IM01 – p-well 14. OX06 – well drive 15. ET06 etch all oxide 16. OX05 – pad oxide 17. CV02 - 1500 Å 18. PH03 – 2 - Active **19. ET29 etch nitride 20. ET07 strip resist**

41. ET07 strip resist 21. PH03 – 3 - p-well stop 42. PH03 - 6 - N + D/S22. IM01- stop 43. IM01 - N + D/S23. ET07 strip resist 44. ET07 strip resist 24. CL01 45. PH03 – 7 P+ D/S 25. OX04 - field 46. IM01 – P+ D/S **26.** ET19 strip nitride 47. ET07 strip resist 27. ET06 etch pad oxide 48. CL01 28. OX04 - Kooi 49. OX08 - poly reox 29. PH03 - 4 - PMOS Vt Adjust 50. CV03 – LTO 30. IM01 - Vt 51. OX08 DS anneal 31. ET07 strip resisit 52. PH03 – 8 CC 32. ET06 etch Kooi Oxide 53. ET10 etch CC 33. CL01 54. ET07 strip resist 34. OX06 - gate 55. CL01 35. CV01 dep poply 56. ME01 Dep Metal1 36. DI04 - dope poly Si 57. PH03 -9- metal1 **37. ET06 etch spin on dopant** 58. ET05 etch metal **38. DE01 four pt probe 59. ET07 strip resist 39.** PH03 – 5 – poly, open 60. CV03 – LTO 40. ET08 poly etch

61. PH03 – 10 VIA
62. ET10 etch VIA
63. ET07 strip resist
64. CL01
65. ME01 Dep Metal2
66. PH03 -11- metal2
67. ET05 etch metal2
68. ET07 strip resist
69. SI01 SINTER
70. TE01 Test 1 van der pauw
71. TE02 Test 2 transistors
72. TE03 Test 3 inverters

73. TE04 Test 4 Vt wafer map

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PROCESS PARAMETERS

Poly Thickness = 0.35 μ m Oxide Thickness Between Poly and Metal One = 0.5 μ m Metal One Thickness = 0.75 μ m Oxide Thickness Between Metal One and Metal Two = 0.5 μ m Metal Two Thickness = 1.0 μ m

Capacitance ~ 6.9 nF/cm^2

Maximum Current Density ~ 1 Amp/ μ m²

Minimum Width \sim 3 Lambda



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MOSIS LAMBDA BASED DESIGN RULES

The design rules may change from foundry to foundry or for different technologies. So to make the design rules generic the sizes, separations and overlap are given in terms of numbers of lambda (λ). The actual size is found by multiplying the number by the value for lambda.

For example:

RÎT PMOS process $\lambda = 10 \ \mu m$ and minimum metal width is 3 λ so that gives a minimum metal width of 30 μm . The RIT CMOS process (single well) has $\lambda = 4 \ \mu m$ and the minimum metal width is also 3 λ so minimum metal is 12 μm but if we send our CMOS designs out to industry λ might be 0.8 μm so the minimum metal of 3 λ corresponds to 2.4 μm . In all cases the design rule is the minimum metal width = 3 λ



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MOSIS LAMBDA BASED DESIGN RULES



MOSIS LAMBDA BASED DESIGN RULES





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MOSIS DESIGN RULES

<u>Click Here to See</u> <u>MOSIS</u> <u>Design Rules</u>



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TV PRE ALIGNMENT (TVPA) MARKS

- The TVPA Marks are placed by the designer on design
- TVPA Marks may be copied from the RITPUB directory
- Dimensions are given for sizes on the wafer
- TVPA Marks are used to adjust for rotation (theta)
- On 6" wafers TVPA marks should be placed on the wafer > 90mm apart, on the front half of the wafer

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HeNe means marks are illuminated with HeNe Laser B² means broadband (white) light illumination



Rochester Institute of Technology Microelectronic Engineering Need 4 die on the wafer with HeNe or B² marks for auto alignment. (actually 2-8 die)



WAFER AUTO ALIGNMENT MARKS for HeNe OR B²



HeNe or B² AA USING B-SCOPE AND C-SCOPE

The B and C scopes are alignment microscopes mounted to the right and back of the lens. These scopes have patterns that match the multimarks (HeNe or B^2 marks) on the wafer and a light intensity detector to determine the alignment signal.

Knowing the location of the y-direction multi-mark on the die, the stage is moved to place the mark under the B-scope (13.0 mm in x-direction). The stage is adjusted slightly in y to give correct alignment signal. The necessary adjustment is recorded. The stage moves the x-direction multi-mark under the C-scope (13.1 mm in y-direction). The stage is adjusted slightly to give correct alignment. The necessary adjustment is recorded. The stage position to center the die under the optical column. The stage moves the die under the optical column. The stage moves the die under the optical column. The stage moves the die under the optical column.



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CANON ALIGNMENT, RESOLUTION AND OVERLAY STRUCTURES



/tools/ritpub/resolution-overlay/canon.gds or canon.iccel_1



USE OF OTHER LAYERS TO SEPARATE RESOLUTION AND OVERLAY FOR EACH MASK



PATTERN GENERATION AND DATA PREP

1. Using Mentor Graphics Design Tools, layout the device layers and save in mentor format. Mentor- ICGraph files (filename.iccel), all layers, polygons with up to 200 vertices

2. Convert the layout information to GDSII file format. GDS2-CALMA files (old IC design tool) (filename.gds), all layers, polygons

3. The GDSII format is then transferred to the CATS system for fracturing (conversion to MEBES format), and other data manipulations such as rotate, mirror, size, bias, and boolean combinations. MEBES- files for electron beam maskmaking tool, each file one layer, trapezoids only

4. Save the file on magnetic tape to transfer to the MEBES.



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CONVERSION FROM .ICCEL TO .GDS FORMAT

GENERATION OF GDS FILE ON HP COMPUTER SYSTEM:

- 1. Type: pwd for design pathname and record: example: /home/stu2/sxs8853/senior
- 2. Type: iclink -co -so -i /pathname/designname -d -g filename.gds note: design name and filename can be the same.
- 3. Obtain individual plots for each mask level, label them, and attach to the order form.
- 4. Copy .gds file to dropbox for maskmaking at RIT cp <design name>.gds /dropbox/masks
- 5. Set protection on file so the file can be accessed /usr/bin/chmod 644 /dropbox/masks/<design name>.gds

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MASK ORDER

Customer Information

Name Company Department Street Address City, State and Zip Code Phone Number () Project Code E-mail Address Order Date Order Due Date				
Masi	k Informatio	n		
Design Name Number of Design Layers in Layout Number of Mask Levels Cell Layout Size Alignment Key (Center of Die is Origin) Fracture Resolution Scale Factor Mirror135 Rotation Plate Size Number of Levels on Plate	.gds X: X: 0.5µm 1X Yes zero 5" x 5" x	μm μm Other 4X None 90 0.090" – E	Y: Y: 5X Other Other mail for othe	μm μM er sizes
Array Array with	None rows and		columns	
Kochester Institute of Technology Microelectronic Engineering				
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MASK ORDER

Mask Level Name	Mask Level #	Design Layer Name	Design Layer #	Boolean Function	Field Type
Nwell	1	n_well.l	1	1 ORed 53	Dark
Active	2	activearea.i	3		Clear
Stop	3			1 ORed 3	Clear
PMOS VT	4	poly.l	6		Dark
Poly	5	?			Clear
N+DS	6	?			Dark
P+DS	7	?			Dark
CC	8	contact_a.l	8		Dark
Metal One	9	metal1.I	9		Clear
Via	10	pad.I	15		Dark
Metal Two	11	?			Clear

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MASK BOX LABELS



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DATA PREP USING CATS



Input File: GDS2- CALMA files (old IC design tool) (filename.gds), all layers, polygons

Output File: MEBES- files for electron beam maskmaking tool, each file one layer, trapezoids only



 $BIAS + 1 \mu m$

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SAVE IN MEBES FORMAT

MEBES format - files for electron beam maskmaking tool, each file one layer trapezoids only



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Design Manual for Standard

STEPPER JOBS



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TEST CHIP

Set Cell Process /class/eecc630/SCNA20

/dropbox/SA_TESTchip_V14 Translate > Read GDSII



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TEST CHIP

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TEST CHIP





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TEST CHIP



NMOS NOMINAL BSIM3 (V3.1) SPICE PARAMETERS

.model nch nmos (LEVEL = 11 + VERSION = 3.1 TNOM = 27 TOX = 3.10E-8 XJ = 9.0E-7 NCH = 8.2E16 VTH0 = 1.026 K2 = -0.1212= 0K3B = 0W0 = 2.5E-6NLX = 4.80E-9+ K1 = 1724K3 + DVT0W = 0 DVT1W = 0 DVT2W = -0.032 DVT0 = 0.1466DVT1 = 0.038DVT2 = 0.1394UA = 2.34E-9UB = -1.85E-18 UC = -1.29E-11 VSAT = 1.64E5A0 = 0.4453+ U0 = 687.22 + AGS = 0**B**1 = 0 KETA = -0.0569A1 A2 B0 = 0= 0= 1 + RDSW = 376.89PRWG = 0PRWB = 0WR = 1WINT = 2.58E-8 LINT = 1.86E-8XW = 0DWG = 0DWB = 0VOFF = -0.1056NFACTOR = 0.8025+ XL= 0CDSC = -2.59E-5 CDSCD = 0 CDSCB = 0ETA0 = 0ETAB = 0+ CIT = 0+ DSUB = 0.0117 PCLM = 0.6184 PDIBLC1 = 0.0251 PDIBLC2 = 0.00202PDIBLCB = 0DROUT = 0.0772+ PSCBE1 = 2.77E9 PSCBE2 = 3.11E-8 PVAG = 0 DELTA = 0.01 MOBMOD = 1PRT = 0+ UTE = -1.5 KT1 = 0KT1L = 0 KT2 = 0 UA1 = 4.30E-9UB1 = -7.60E-18+ UC1 = -5 6E-11 AT = 3.3E4WL = 0 WLN = 1WW = 0WWN = 1+ WWL = 0LL = 0 $LLN = 1 \quad LW = 0$ LWN = 1LWL = 0+ CAPMOD = 2XPART = 0 CGDO = 1.99E-10 CGSO = 1.99E-10 CGBO = 0 CJ= 4.233802E-4PB = 0.9899238MJ = 0.4495859 CJSW = 3.825632E-10 PBSW = 0.1082556 MJSW = 0.1083618+ PVTH0 = 0.0212852 PRDSW = -16.1546703 PK2 = 0.0253069 WKETA = 0.0188633 LKETA = 0.0204965 + HDIF = hdifn)

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PMOS NOMINAL BSIM3 (V3.1) SPICE PARAMETERS

.model pch pmos (LEVEL = 11+ VERSION = 3.1TNOM = 27 TOX = 3.10E-8 XJ = 8.80E-7 NCH = 3.10E16 VTH0 = -1.166+ K1 = 0.3029K2 = 0.1055 K3= 0K3B = 0W0 = 2.50 E-6NLX = 2.01E-8+ DVT0W = 0DVT1W = 0DVT2W = -0.032 DVT0 = 2DVT1 = 0.5049DVT2 = -0.0193+ U0 = 232.53 UA = 4.00E-9UB = -2.26E-18 UC = -6.80E-11 VSAT = 4.40E4A0 = 0.6045+ AGS = 0B0 = 0B1 = 0 KETA = -0.0385 A1 = 0 A2 = 1 **RDSW** = 1.23E3 PRWG = 0PRWB = 0 WR = 1WINT = 1.67E-8LINT = 6.50E-8+ XL XW = 0DWG = 0 DWB = 0VOFF = -0.0619NFACTOR = 1.454= 0CDSC = -4.30E-4 CDSCD = 0 CDSCB = 0ETA0 = 0ETAB = 0+ CIT = 0+ DSUB = 0.2522 PCLM = 5.046PDIBLC1 = 0 PDIBLC2 = 1.00E-5 PDIBLCB = 0DROUT = 0.2522+ PSCBE1 = 2.80E9 PSCBE2 = 2.98E-8 PVAG = 0 DELTA = 0.01MOBMOD = 1PRT = 0+ UTE = -1.5 KT1 = 0 $KT1L = 0 \quad KT2 = 0$ UA1 = 4.30 E-9UB1 = -7.60E - 18=-5.6E-11 AT = 3.3E4WL = 0 WLN = 1WW = 0WWN = 1+ UC1 + WWL = 0LL = 0LLN = 1 LW = 0LWN = 1LWL = 0+ CAPMOD = 2XPART = 0CGDO = 2.4E-10 CGSO = 2.4E-10CGBO = 0CJ = 7.273568E-4= 0.9665597MJ = 0.4959837 CJSW = 3.114708E-10 PBSW = 0.99 MJSW = 0.2653654 PVTH0 = 9.420541E-3+ PB+ PRDSW = -231.2571566 PK2 = 1.396684E-3 WKETA = 1.862966E-3 LKETA = 5.728589E-3 + HDIF = hdifp)

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All parameters the same except those listed are changed to give more transistor current:

.model hot nmos (LEVEL = 11 VERSION = 3.1TOX = 2.70E-8 VTH0= 0.926 U0 = 750 RDSW = 330)

.model hot pmos (LEVEL = 11 VERSION = 3.1 TOX = 2.70E-8 VTH0= -1.066 U0 = 250 RDSW = 1.00E3)

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All parameters the same except those listed are changed to give less transistor current:

.model cold nmos (LEVEL = 11 VERSION = 3.1 TOX = 3.50E-8 VTH0= 1.126 U0 = 620 RDSW = 410)

.model cold pmos (LEVEL = 11 VERSION = 3.1 TOX = 3.50E-8 VTH0= -1.266 U0 = 200 RDSW = 1.45E3)



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NMOS COLD

	.moc	del nch r	nmc	os (LEVEI	L = 11		
	+	VERSION	=	3.1	5	INOM	=	27		TOX	=	3.70E-8
	+	XJ	=	8.6E-7	1	NCH	=	8.6E16		VTH0	=	1.282
	+	K1	=	1.63	I	K2	=	0.0167		KЗ	=	0
	+	КЗВ	=	0	V	ΟW	=	2.5E-6		NLX	=	8.80E-9
	+	DVTOW	=	0	Ι	DVT1W	=	0		DVT2W	=	-0.032
	+	DVT0	=	0.1007	Ι	DVT1	=	0.0455		DVT2	=	-0.1657
	+	U0	=	701.12	τ	JA	=	2.21E-9		UB	=	-1.29E-18
	+	UC	=	-4.80E-11	7	VSAT	=	7.20E4		AO	=	0.342
	+	AGS	=	0	H	В0	=	0		В1	=	0
	+	KETA	=	-0.0308	7	A1	=	0		A2	=	1
	+	RDSW	=	1.13E3	I	PRWG	=	0		PRWB	=	0
	+	WR	=	1	V	VINT	=	9.90E-8		LINT	=	1.25E-7
	+	XL	=	0	Σ	XW	=	0		DWG	=	0
	+	DWB	=	0	7	JOFF	=	-0.1015		NFACTOR	=	0.7948
	+	CIT	=	0	C	CDSC	=	-1.01E-5		CDSCD	=	0
	+	CDSCB	=	0	H	eta0	=	0		ETAB	=	0
	+	DSUB	=	6.80E-4	I	PCLM	=	0.5599		PDIBLC1	=	0.00541
	+	PDIBLC2	=	0.0021	I	PDIBLCB	=	0		DROUT	=	0.0355
	+	PSCBE1	=	2.59E9	I	PSCBE2	=	2.80E-8		PVAG	=	0
	+	DELTA	=	0.01	1	MOBMOD	=	1		PRT	=	0
	+	UTE	=	-1.5	I	KT1	=	0		KT1L	=	0
	+	KT2	=	0	τ	JA1	=	4.30E-9		UB1	=	-7.60E-18
	+	UC1	=	-5.6E-11	7	ΑT	=	3.3E4		WL	=	0
	+	WLN	=	1	V	WW	=	0		WWN	=	1
	+	WWL	=	0]	LL	=	0		LLN	=	1
	+	LW	=	0]	LWN	=	1		LWL	=	0
	+	CAPMOD	=	2	2	XPART	=	0		CGDO	=	1.99E-10
	+	CGSO	=	1.99E-10	(CGBO	=	0		CJ	=	4.233802E-4
	+	PB	=	0.9899238	1	J	=	0.4495859		CJSW	=	3.825632E-10
	+	PBSW	=	0.1082556	1	MJSW	=	0.1083618		PVTH0	=	0.0212852
-	+	PRDSW	=	-16.1546703	I	PK2	=	0.0253069		WKETA	=	0.0188633
	+	LKETA	=	0.0204965								
	+	HDIF	=	hdifn)								



PMOS COLD

.model pch pmos (LEVEL = 11										
	+	VERSION	=	3.1	TNOM	=	27	TOX	=	3.40E-8
	+	XJ	=	9.00E-7	NCH	=	2.60E16	VTH0	=	-1.461
	+	K1	=	0.0766	К2	=	0.2287	KЗ	=	0
	+	КЗВ	=	0	WO	=	2.50E-6	NLX	=	4.40E-8
	+	DVTOW	=	0	DVT1W	=	0	DVT2W	=	-0.032
	+	DVT0	=	0.16	DVT1	=	0.1091	DVT2	=	-0.6009
	+	U0	=	214.32	UA	=	3.30E-9	UB	=	-1.37E-18
	+	UC	=	-6.90E-11	VSAT	=	1.94E4	AO	=	0.1
	+	AGS	=	0	в0	=	0	В1	=	0
	+	KETA	=	-0.0489	A1	=	0	A2	=	1
	+	RDSW	=	481.9	PRWG	=	0	PRWB	=	0
	+	WR	=	1	WINT	=	6.10E-8	LINT	=	1.28E-7
	+	XL	=	0	XW	=	0	DWG	=	0
	+	DWB	=	0	VOFF	=	-0.0564	NFACTOR	=	0.5158
	+	CIT	=	0	CDSC	=	9.70E-6	CDSCD	=	0
	+	CDSCB	=	0	eta0	=	0	ETAB	=	0
	+	DSUB	=	0.00745	PCLM	=	14.255	PDIBLC1	=	0
	+	PDIBLC2	=	0.00149	PDIBLCB	=	0	DROUT	=	0.1091
	+	PSCBE1	=	2.64E9	PSCBE2	=	2.79E-8	PVAG	=	0
	+	DELTA	=	0.01	MOBMOD	=	1	PRT	=	0
	+	UTE	=	-1.5	KT1	=	0	KT1L	=	0
	+	KT2	=	0	UA1	=	4.30E-9	UB1	=	-7.60E-18
	+	UC1	=	-5.6E-11	AT	=	3.3E4	WL	=	0
	+	WLN	=	1	WW	=	0	WWN	=	1
	+	WWL	=	0	LL	=	0	LLN	=	1
	+	LW	=	0	LWN	=	1	LWL	=	0
	+	CAPMOD	=	2	XPART	=	0	CGDO	=	2.4E-10
	+	CGSO	=	2.4E-10	CGBO	=	0	CJ	=	7.273568E-4
	+	PB	=	0.9665597	MJ	=	0.4959837	CJSW	=	3.114708E-10
	+	PBSW	=	0.99	MJSW	=	0.2653654	PVTH0	=	9.420541E-3
•	+	PRDSW	=	-231.2571566	PK2	=	1.396684E-3	WKETA	=	1.862966E-3
	+	LKETA	=	5.728589E-3						
	+ E	IDIF = h	di	fp)						



NMOS HOT

.moc	del nch r	nmo	os (LEVEI	L = 11		
+	VERSION	=	3.1		TNOM	=	27		TOX	=	2.99E-8
+	XJ	=	1.0E-6		NCH	=	6.5E16		VTH0	=	0.8411
+	K1	=	1.117		К2	=	0.0138		KЗ	=	0
+	КЗВ	=	0		WO	=	2.5E-6		NLX	=	2.12E-8
+	DVTOW	=	0		DVT1W	=	0		DVT2W	=	-0.032
+	DVT0	=	0.1692		DVT1	=	0.042		DVT2	=	-0.1482
+	U0	=	790.78		UA	=	2.55E-9		UB	=	-4.50E-18
+	UC	=	-1.62E-10		VSAT	=	1.46E5		AO	=	0.5306
+	AGS	=	0		в0	=	0		В1	=	0
+	KETA	=	-0.0465		A1	=	0		A2	=	1
+	RDSW	=	182.48		PRWG	=	0		PRWB	=	0
+	WR	=	1		WINT	=	2.23E-8		LINT	=	-1.53E-8
+	XL	=	0		XW	=	0		DWG	=	0
+	DWB	=	0		VOFF	=	-0.0958		NFACTOR	=	0.7539
+	CIT	=	0		CDSC	=	-2.92E-5		CDSCD	=	0
+	CDSCB	=	0		ETA0	=	0		ETAB	=	0
+	DSUB	=	0.0112		PCLM	=	1.762		PDIBLC1	=	0.0211
+	PDIBLC2	=	0.00248		PDIBLCB	=	0		DROUT	=	0.066
+	PSCBE1	=	8.40E9		PSCBE2	=	3.20E-8		PVAG	=	0
+	DELTA	=	0.01		MOBMOD	=	1		PRT	=	0
+	UTE	=	-1.5		KT1	=	0		KT1L	=	0
+	KT2	=	0		UA1	=	4.30E-9		UB1	=	-7.60E-18
+	UC1	=	-5.6E-11		AT	=	3.3E4		WL	=	0
+	WLN	=	1		WW	=	0		WWN	=	1
+	WWL	=	0		LL	=	0		LLN	=	1
+	LW	=	0		LWN	=	1		LWL	=	0
+	CAPMOD	=	2		XPART	=	0		CGDO	=	1.99E-10
+	CGSO	=	1.99E-10		CGBO	=	0		CJ	=	4.233802E-4
+	PB	=	0.9899238		MJ	=	0.4495859		CJSW	=	3.825632E-10
+	PBSW	=	0.1082556		MJSW	=	0.1083618		PVTH0	=	0.0212852
+	PRDSW	=	-16.1546703		PK2	=	0.0253069		WKETA	=	0.0188633
+	LKETA	=	0.0204965								
+	HDIF	=	hdifn)							



PMOS HOT

1	.moc	del pch p	omo	os (LEVEI	. = 11		
	+	VERSION	=	3.1	TNOM	=	27		TOX	=	3.20E-8
	+	XJ	=	9.50E-7	NCH	=	3.50E16		VTH0	=	-0.8576
	+	K1	=	0.5848	K2	=	-0.00369		KЗ	=	0
	+	КЗВ	=	0	WO	=	2.50E-6		NLX	=	2.19E-8
	+	DVTOW	=	0	DVT1W	=	0		DVT2W	=	-0.032
	+	DVT0	=	2	DVT1	=	0.3564		DVT2	=	0.0283
	+	U0	=	258.34	UA	=	5.00E-9		UB	=	-2.31E-18
	+	UC	=	-1.07E-10	VSAT	=	1.96E4		AO	=	0.1
	+	AGS	=	0	в0	=	0		В1	=	0
	+	KETA	=	-0.0533	A1	=	0		A2	=	1
	+	RDSW	=	369.91	PRWG	=	0		PRWB	=	0
	+	WR	=	1	WINT	=	6.80E-8		LINT	=	1.42E-7
	+	XL	=	0	XW	=	0		DWG	=	0
	+	DWB	=	0	VOFF	=	-0.045		NFACTOR	=	0.6032
	+	CIT	=	0	CDSC	=	-6.40E-4		CDSCD	=	0
	+	CDSCB	=	0	ETA0	=	0		ETAB	=	0
	+	DSUB	=	0.3564	PCLM	=	4.446		PDIBLC1	=	0
	+	PDIBLC2	=	0.00209	PDIBLCB	=	0		DROUT	=	0.3564
	+	PSCBE1	=	2.65E9	PSCBE2	=	2.75E-8		PVAG	=	0
	+	DELTA	=	0.01	MOBMOD	=	1		PRT	=	0
	+	UTE	=	-1.5	KT1	=	0		KT1L	=	0
	+	KT2	=	0	UA1	=	4.30E-9		UB1	=	-7.60E-18
	+	UC1	=	-5.6E-11	AT	=	3.3E4		WL	=	0
	+	WLN	=	1	WW	=	0		WWN	=	1
	+	WWL	=	0	LL	=	0		LLN	=	1
	+	LW	=	0	LWN	=	1		LWL	=	0
	+	CAPMOD	=	2	XPART	=	0		CGDO	=	2.4E-10
	+	CGSO	=	2.4E-10	CGBO	=	0		CJ	=	7.273568E-4
	+	PB	=	0.9665597	MJ	=	0.4959837		CJSW	=	3.114708E-10
	+	PBSW	=	0.99	MJSW	=	0.2653654		PVTH0	=	9.420541E-3
	+	PRDSW	=	-231.2571566	PK2	=	1.396684E-	-3	WKETA	=	1.862966E-3
	+	LKETA	=	5.728589E-3							
	+	HDIF	=	hdifp)							



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PACKAGE







Rochester Institute of Technology Microelectronic Engineering 0.10 inch adjacent pin spacing0.6 inch row spacing

CHIP SIZE AND BOND PAD LOCATIONS

Maximum Chip Size for this Package = 6 mm X 6 mm

Pads on chip should be 10 on each side evenly spaces but not smaller than 100 μ m by 100 μ m bond pad. Leave plenty of room near the corners





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esign Manual for SMFL Standard CMOS

MOSIS TINYCHIP PAD FRAME





/users/class/eecc630/pads/40pc22x22_stuffed/40pc22x22_stuffed /users/class/eecc630/pads/scna20-pads.doc

WIRE BONDING





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WIRE BONDING

Large diameter gold wire (10 mil) can be ultrasonically bonded to aluminum pads on chips and then can be soldered into a circuit

Smaller diameter aluminum wire (3 mil) can be ultrasonically bonded to aluminum chip pads and then to packages





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MOSIS I/O PAD CELL



MOSIS +V AND I/O PAD CELLS



TINY CHIP PAD SET

These pads have been validated by the MOSIS System of USC/ISI. Any modification of these pads by the user is done solely at the user's risk. Modified pads are not to be referred to as "MOSIS Pads" unless prior agreement is obtained from USC/ISI. MOSIS really intends that you use the complete (stuffed) digital or analog pad frames without modification. The individual pads and pad frame subcells are supplied only as a courtesy to those who want to build and verify their own custom pad frames. These pads were not designed to be interchangeable within the pad frame, rather, they were optimized for power and size, and require intricate editing and verification in different arrangements.); TINYCHIP PADS SET, SCN (N-WELL) 2.0 MICRON

1. INTRODUCTION

This 2 micron SCN (N-well) TinyChip pads set was designed with the MOSIS scalable CMOS design rules (Rev 6) at a lambda of 1.0 micron. To use these pads, get the newest Magic technology file (dated on or after than 1/19/93). All pads are laid out on a lambda grid and are designed for use with the 40PC22X22 Standard Frame.

2. CONTENTS OF THE DIGITAL PADS SET

blank.CIF	blank with only bonding metals
gnd.CIF	internal GND power supply - not connected to pad GND
vdd.CIF	internal Vdd power supply - not connected to pad Vdd
in.CIF	input pad - a derivative from I/O pad
io.CIF	input/output pad
out.CIF	output pad - a derivative from I/O pad
cg.CIF	GND Bottom Left corner pad
CG_r.CIF	GND Bottom Right corner pad
cv.CIF	Vdd Top Left corner pad
cv_r.CIF	Vdd Top Right corner pad
40pc22x22_stuffed.CIF	contains a complete io pad ring layout in size 220x2250 um



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TINY CHIP PAD SET

DESCRIPTION:

The single most important pad in this pad set is the IO pad. From this tri-state I/O pad we derived the IN pad and the OUT pad. A circuit diagram for this tri-state I/O pad is given below. Connecting ENABLE to GND will turn this I/O pad into an input pad. Connecting ENABLE to Vdd will result an output pad.

ESD protection is done with

- (1) Thick-Field Oxide transistor of size W/L = 600/3 microns,
- (2) 150 ohms N_diffusion resistor/diode, and
- (3) Tri-state output drivers as pair of diode clamps.



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TINY CHIP PAD SET

These pads should fit into the standard frame 40PC22x22 with mirroring. They can also be used for other MOSIS standard frames. io, in, out, Vblank, vdd, and gnd has none-well maximum bonding box (MBB) of 200x210 microns each. The well MBB is 210x218 microns. The stuffed frame has a non-well MBB of 2220x2250 microns. There are 9 pads on each edge plus 4 corners used as Vdd and GND pads. The top edge has a GND pad in the middle and its 2 corners are Vdd pads, while the bottom edge has a Vdd pad in the middle and its 2 corners are GND pads. This gives 3 Vdd and 3 GND pads total.

3. CONTENTS OF THE ANALOG PADS SET

gndN.CIF vddN.CIF analogN.CIF llN.CIF urN.CIF 40pc22x22_stuffed_analog.CIF internal GND power supply - not connected to pad GND internal Vdd power supply - not connected to pad Vdd analog input/output pad GND Bottom Left corner pad Vdd Top Right corner pad contains a complete io pad ring layout in size 2220x2250 um

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* Description

ESD protection is achieved by two lateral PNP parasitic transistor in N-well (1) reverse biased diode connected to Vdd when a positive ESD stress is applied. (2) PNP transistor from GND to input when a negative ESD stress is applied.



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TINY CHIP PAD SET

4. SIMULATION and MEASUREMENT

Both pad set have been fabricated by MOSIS for verification, but only pads in digital set are simulated and measured. Their result are listed as follows:

* Delay

OUTPUT Driver Load (SIMULATED)

10pF 30pF 50pF -----+ rise time | 8ns 21ns 30ns fall time | 7ns 17ns 25ns -----+

OUTPUT Driver Load (MEASURED)



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TINY CHIP PAD SET

INPUT Driver Load (SIMULATED)

		load:		load:	load:
		INbar/IN	INbar/IN	INbar/IN	
		0.5/1pF		1/2pF	2/4pF
		prop/rise/fall	prop/rise/fall	prop/rise/fall	1
signal	signal	delay/time/tir	ne	delay/time/time	delay/time/time
PAD	INbar	1.1/3.9/2.0	1.6/5.5/3.0	2.2/8.5/4.5	
INbar	IN	2.2/3.0/2.2	2.2/5.0/3.5	3.8/8.5/6.5	

* DC Current Capability

Maximum current :: 11 mA per I/O pad with 50pF loading

5. Magic CIF input

In Magic, Berkeley's layout editor, use ":cif is lambda=1.0(nwell)" to specify the appropriate CIF input style before using ":cif read ..." command.



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KODAK-RIT I/O CELL SCHEMATIC



KODAK-RIT I/O CELL LAYOUT



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ESD PROTECTION

$\$ Analog io pads

§Ground/Power pad §Analog Reference Pad §IO Pad

$\mathbf{\widehat{S}DIGITAL}$ IO PADS

ESD protection

-Field transistor

-150 ohm



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Adapted from AMI

0.5um High ESD Library

PADS





PAD LAYOUT



PAD POWER HOOKUP



CHIP HOOKUP



DIGITAL I/O PAD CIRCUIT



USING THE HP WORKSTATIONS AND MENTOR GRAPHICS CAD TOOLS - PAD CELL AND LETTERS

From the banner at the top of the page choose Objects>add>cell. A tan pop-up window will appear at the bottom of the page. Type in the following cell name, all lower case, /tools/ritpub/padframes/ritpmos/ritpmos_12_pads and click the left mouse button on the location button. Then position the cursor at the origin 0,0 and click the left mouse button. Click the left mouse button on the cancel button on the tan pop-up box. Press SHIFT and F8 to View All. You should see a white box with ritpmos_12_pads written inside it. Type flatten and select, OK. Press F2 to unselect all.



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